

ABSTRACT OF THE DISCLOSURE

To make it possible to preferably form a film on
spacers provided in an airtight container of an
electron beam apparatus. A method of manufacturing an
5 electron beam apparatus having an airtight container
with electron-emitting devices contained therein and
spacers provided in the airtight container comprises
the coating step of providing a film on a spacer
substrate to be the spacers, and is characterized in
10 that the coating step includes the applying step of
applying liquid film material by emitting from an
emitting portion in a predetermined direction to a part
of a surface of the spacer substrate facing the
emitting portion.

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